Group Art Unit: 2812

Examiner: Not Assigned 2800 IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

the application of:

Robert A. SHEPHERD, Jr. et al.

Application No. 10/006,100

Filed: December 3, 2001

For: METHOD AND APPARATUS FOR

PLASMA OPTIMIZATION IN WAFER PROCESSING

Atty. Docket No. NOVEP015

Date: July 26, 2002

**CERTIFICATE OF MAILING** 

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231 on July 26, 2002.

Signed:

Diane Schwanbeck

## INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents Washington, DC 20231

Dear Sir:

The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§ 1.56 and 1.97. The Examiner is requested to consider these references and to acknowledge such consideration by initialing the appropriate locations on the attached PTO Form 1449.

This Information Disclosure Statement (IDS) is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This IDS is believed to be filed before the mailing date of a first Office Action on the merits. Accordingly, it is believed that no fees are due in connection with the filing of this IDS. However, if it is determined that any fees are due, then the Commissioner is hereby authorized to charge such fees to Deposit Account 50-0805 (Order No. NOVEP015).

Respectfully submitted,

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